



LONGHILL INDUSTRIES LIMITED.

Longhill Model LH800 AUTOMATIC Wafer Transfer / Packing System



Model LH800 - What order and in what container do you need your wafers?

Longhill's experience with designing and building the various wafer handling concepts needed for wafer mounting, wafer laminating, taping and de-taping systems, etc. This has transferred to a wealth of knowledge as to how and where to put wafers accurately and gently. The Longhill Model LH800 is the system that incorporates this experience and knowledge.

The LH800 can:

- Sort
- Transfer
- Stack and un-stack
- Invert
- Catalog
- Record
- Label
- **Pack and unpack wafers**

Thin wafers! Thick wafers! Cassettes! Wafer boxes!
Bernoulli Effects Robotics!

Deliver the wafers in the configuration required!

Optional configurations samples:

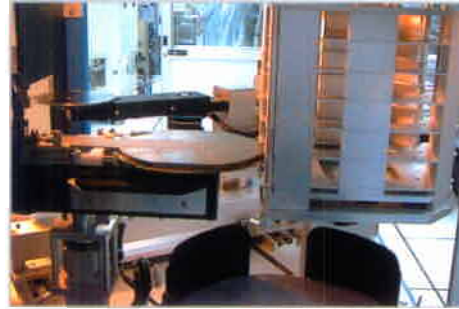
- Cassette to cassette.
- Cassettes to coin stack in wafer box, with separators between wafers.
- Coin stack to cassettes.
- Process cassettes to shipping containers and back.
- Orient wafers with reference to flats or notches.
- Invert wafers.
- Read and record wafer codes.
- Sort by wafer codes.
- Randomized the wafers in cassettes.
- Store photo of wafers.
- Print identification or shipping labels.
- Special needs can most likely be accommodated.

LONGHILL INDUSTRIES LIMITED.

Longhill Model LH800 sample wafer handling methods:



Fork robot and cassette



Bernoulli robot and cassette



Flat finder



Bernoulli robot and wafer box

SPECIFICATION OF LH800 WAFER TRANSFER MACHINE

Wafer size	4", 5", 6", 8"
Wafer type	2-30 mil thickness, flat or notch
Wafer table temp	Ambient
Wafer cassette / box	4 cassettes / box, horizontal
Cycle time	40 - 50 secs (depend on wafer circuit up / down at box)
Machine capability	a. Input wafer circuit side up & down. b. Box - cassette, box - box, cassette - cassette, cassette - box c. Single carrier to multiple carrier or multiple carrier to single carrier
Wafer alignment reference	Detect of flat (single or double) or notch
Wafer alignment detection method	Non contact optical sensing method
Wafer handling arm	Robotic fork / Bernoulli arm
Interleaf / cushion	Automatic detection
Control unit	Industrial PC
* Barcode reader / OCR (option)	Wafer tracking system
* Wafer curing station (option)	DAF taped wafer
Air	4.5kgf / cm ² dry air, 50 litre / minute
Power supply	AC 220V, 50/60 Hz, 10A
Dimensions	1100 mm (W) x 1100 mm (D) x 1600 mm (H)
Net / shipping weight	420 Kg / 500 Kg

Specifications subject to change without notice

Note:

* - Consult factory for other requirement.



LONGHILL INDUSTRIES LTD.

22/F Lever Centre,
69 - 71 King Yip Street,
Kwun Tong, Kowloon, Hong Kong
Tel : (852) 2763 0671, 2357 5298
Fax: (852) 2357 4039
E-mail : longhill@longhill-ind.com

Distributed by: